

**OLYMPUS**<sup>®</sup>

Your Vision, Our Future

300 mm WAFER LOADER

**AL120-12**

SERIES

**NEW**

***300 mm compatible wafer loader & microscope system***



- 300 mm wafer
- Top surface macro
- Back surface macro
- 1 cassette

**AL120-LMB12-LP**



**AL120-LMB12-F**

# With attention to wafer safety, the AL120-12 is committed to enhancing the essence of operations in back-end process and providing improving yield and productivity improvement.

## Easy operation

- The AL120-12 emphasizes usability through features including fully customizable Inspection mode and device design that takes into account operability tailored for exclusive use in back-end process.
- The AL120-12 also provides you the system with FOSB for exclusive use.

## The highest system reliability and inherited system performance

- The AL120-12 allows safety and automated micro inspection of 300 mm wafers, with keeping the high level of reliability and safety provided in the AL110 series.
- The AL120-12 enables a transfer of both warped wafer and thin wafer with OLYMPUS safety and reliable handling system.
- The AL120-12 provides you easy operation and high visibility with the optimized position for macro inspection and the friendly control panel.

## Dedicated macro illumination unit (optional)

- Users can select the macro illumination to provide optimal illumination to inspect for particles, scratches, film undulations and defocus.
- The combination of a high-intensity metal halide light source and fiber optics allows illumination of a full-surface of 300 mm wafer with cold-light illumination.

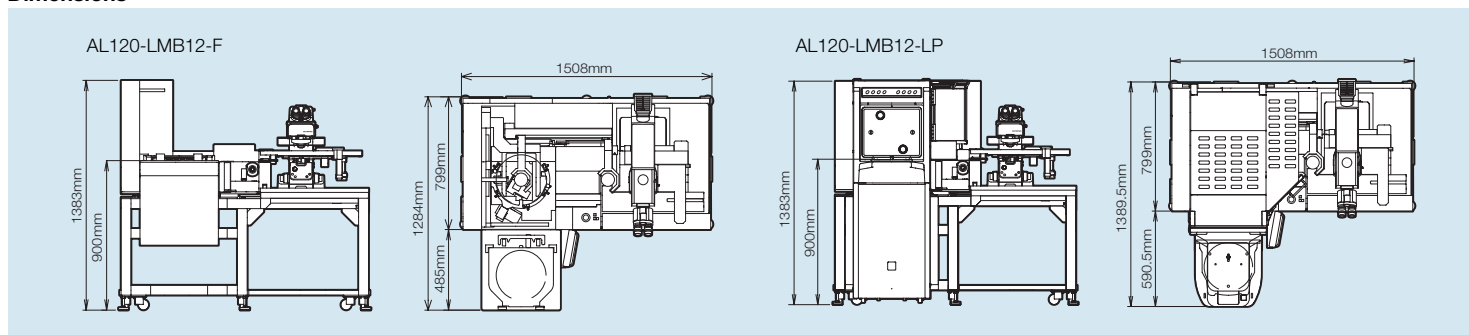


Dedicated macro illumination unit

## Specifications

	AL120-LMB12-F	AL120-LMB12-LP
Wafer size	300mm (SEMI M1.15 t=775μm) 200 mm (Optional)	
Standard type of cassette	FOSB (Front Opening Shipping Box) SEMI:M31-0999 Standard	FOUP (Front Opening Unified Pods) SEMI:E47.1-0200 Standard FIMS-FOSB, FOSB
Number of cassette	1 Cassette (load /unload on the same route)	
Height of cassette loading position	900mm	
Load port	Not available	Available
Transfer modes	Top macro inspection, back macro inspection, micro inspection	
Inspection mode	Sequential or Sampling	
Wafer alignment	Non-contact centering	
Wafer handling method	Robot arms with vacuum pickup	
Compatible microscope	Semiconductor wafer inspection microscope MX61L	
Utility	AC100V-120V, 220-240V 3.0/1.7A 50/60Hz Vacuum -67~-80Kpa	
Stage	XY manual stage with vacuum attraction /360 degree rotatable function	
Weight (excluding the microscope)	Approximately 270Kg	Approximately 360Kg

## Dimensions



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